

Notice of References Cited	Application/Control No. 10/695,439		Applicant(s)/Patent Under Reexamination SAKAI ET AL.	
	Examiner Howard Weiss		Art Unit 2814	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,943,376	09-2005	Nakatsuka et al.	257/177
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Tsukimoto, S., et al., "Electrical properties and microstructure of ternary Ge/Ti/Al ohmic contacts to p-type 4H-SiC", Nov., 2004, J. App. Phys., Vol. 96, No. 9, p. 4976-81
	V	Konishi, R., et al., "Development of Ni/Al and Ni/Ti/Al ohmic contact materials for p-type 4H-SiC", 2003, Mat. Sci. Eng., B98, p.286-93
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.